

Bashkim Ziberi

List of Publications by Year in descending order

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29
papers

1,466
citations

361413

20
h-index

526287

27
g-index

29
all docs

29
docs citations

29
times ranked

840
citing authors

#	ARTICLE	IF	CITATIONS
1	Pattern formation on Ge by low energy ion beam erosion. <i>New Journal of Physics</i> , 2013, 15, 103029.	2.9	55
2	Extreme X-ray beam compression for a high-resolution table-top grazing-incidence small-angle X-ray scattering setup. <i>Journal of Applied Crystallography</i> , 2013, 46, 1544-1550.	4.5	7
3	Ion Beam Sputtering: A Route for Fabrication of Highly Ordered Nanopatterns. <i>Advanced Structured Materials</i> , 2011, , 69-94.	0.5	4
4	Self-organized patterning on Si(001) by ion sputtering with simultaneous metal incorporation. <i>Applied Physics A: Materials Science and Processing</i> , 2011, 102, 593-599.	2.3	33
5	GISAXS and AFM study of self-assembled Fe ₂ O ₃ nanoparticles and Si nanodots. <i>Physica Status Solidi (A) Applications and Materials Science</i> , 2011, 208, 2619-2622.	1.8	5
6	Formation of two ripple modes on Si by ion erosion with simultaneous Fe incorporation. <i>Applied Surface Science</i> , 2011, 257, 8659-8664.	6.1	11
7	Topography evolution mechanism on fused silica during low-energy ion beam sputtering. <i>Journal of Applied Physics</i> , 2011, 109, 043501-043501-6.	2.5	33
8	Is keV ion-induced pattern formation on Si(001) caused by metal impurities?. <i>Nanotechnology</i> , 2010, 21, 085301.	2.6	116
9	Measurement of nanopatterned surfaces by real and reciprocal space techniques. <i>Measurement Science Review</i> , 2010, 10, .	1.0	11
10	Importance of Internal Ion Beam Parameters on the Self-organized Pattern Formation with Low-energy Broad Beam Ion Sources. <i>Materials Research Society Symposia Proceedings</i> , 2009, 1181, 140.	0.1	0
11	Investigation of nucleation and phase formation of photocatalytically active TiO ₂ films by MePBIID. <i>Nuclear Instruments & Methods in Physics Research B</i> , 2009, 267, 1658-1661.	1.4	4
12	Large area smoothing of surfaces by ion bombardment: fundamentals and applications. <i>Journal of Physics Condensed Matter</i> , 2009, 21, 224026.	1.8	104
13	Ion-induced nanopatterns on semiconductor surfaces investigated by grazing incidence x-ray scattering techniques. <i>Journal of Physics Condensed Matter</i> , 2009, 21, 224007.	1.8	27
14	Highly ordered nanopatterns on Ge and Si surfaces by ion beam sputtering. <i>Journal of Physics Condensed Matter</i> , 2009, 21, 224003.	1.8	107
15	Surface engineering with ion beams: from self-organized nanostructures to ultra-smooth surfaces. <i>Applied Physics A: Materials Science and Processing</i> , 2008, 91, 551-559.	2.3	145
16	Self-organized pattern formation by ion beam erosion. , 2008, , .		1
17	Ripple rotation, pattern transitions, and long range ordered dots on silicon by ion beam erosion. <i>Applied Physics Letters</i> , 2008, 92, .	3.3	77
18	Pattern transitions on Ge surfaces during low-energy ion beam erosion. <i>Applied Physics Letters</i> , 2006, 88, 173115.	3.3	59

#	ARTICLE	IF	CITATIONS
19	Formation of large-area nanostructures on Si and Ge surfaces during low energy ion beam erosion. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2006, 24, 1344-1348.	2.1	41
20	Self-organized dot patterns on Si surfaces during noble gas ion beam erosion. Surface Science, 2006, 600, 3757-3761.	1.9	20
21	Ion-induced self-organized dot and ripple patterns on Si surfaces. Vacuum, 2006, 81, 155-159.	3.5	26
22	In situ diagnostics of zeolite crystallization by ultrasonic monitoring. Microporous and Mesoporous Materials, 2005, 80, 1-9.	4.4	21
23	Ion beam sputter deposition of soft x-ray Mo/Si multilayer mirrors. Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena, 2005, 23, 959.	1.6	13
24	Highly ordered self-organized dot patterns on Si surfaces by low-energy ion-beam erosion. Applied Physics Letters, 2005, 87, 033113.	3.3	80
25	Ripple pattern formation on silicon surfaces by low-energy ion-beam erosion: Experiment and theory. Physical Review B, 2005, 72, .	3.2	193
26	The shape and ordering of self-organized nanostructures by ion sputtering. Nuclear Instruments & Methods in Physics Research B, 2004, 216, 9-19.	1.4	108
27	Ion beam assisted smoothing of optical surfaces. Applied Physics A: Materials Science and Processing, 2004, 78, 651-654.	2.3	52
28	Large area smoothing of optical surfaces by low-energy ion beams. Thin Solid Films, 2004, 459, 100-105.	1.8	67
29	Importance of ion beam parameters on self-organized pattern formation on semiconductor surfaces by ion beam erosion. Thin Solid Films, 2004, 459, 106-110.	1.8	46